OF E VCIA

PATENT APPLICATION

TECHNOLOGY

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE \mathcal{C}_{EN}

In re the Application of

Akira SHIMOKOHBE et al.

Application No.: 09/556,795

Filed: April 25, 2000

d. Amil 25 2000

Group Art Unit: 2813

Examiner:

Asok K. Sarkar

Docket No.: 106096

A THIN FILM-STRUCTURE AND A METHOD FOR PRODUCING THE SAME

AMENDMENT

Director of the U.S. Patent and Trademark Office Washington, D.C. 20231

Sir:

For:

In reply to the Office Action mailed July 10, 2001, please amend the above-identified application as follows:

IN THE CLAIMS:

Please replace claim 3 as follows:

3. (Twice Amended) A method for producing a thin film-structure comprising the steps of:

forming on a substrate a thin film made of an amorphous material having a supercooled liquid phase region,

heating the thin film to a temperature within the supercooled liquid phase region and thereby deforming the thin film to a given shape without the use of an external force, and

cooling the thin film to room temperature from the temperature within the supercooled liquid phase region to stop deforming the thin film and thereby forming the thin film-structure.

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